Inventor: Kazuto KINOSHITA, et al.

Preliminary Amendment filed with Divisional Application September 10, 2003

IN THE CLAIMS

1.-27. (Cancel)

28. (Currently Amended) A method for treating substrate surfaces, comprising the steps of:

placing a substrate in a mixed atmosphere of an inert gas and water vapor under irradiation of ultraviolet light from a dielectric barrier discharge lamp, thereby splitting water vapor into a reducing active member [H-] (H-) and an oxidative active member [-OH] (-OH); and

letting said reducing and oxidative active members [H·] (H·) and [·OH] (·OH) contact with a surface of said substrate to be treated.

29. (Currently Amended) A method for treating substrate surfaces, comprising the steps of: horizontally transferring a substrate into a mixed atmosphere of an inert gas and water vapor under irradiation of ultraviolet light from a dielectric barrier discharge lamp, thereby decomposing organic substances deposited on a surface of said substrate and at the same time splitting water vapor into a reducing active member [+OH] (+OH); and

subjecting said reducing and oxidative active members [H-] (H·) and [-OH] (OH) to reactions with decomposition products of said organic substances.

30. (Currently Amended) A method for treating substrate surfaces, comprising the steps of:

horizontally transferring a substrate into a mixed atmosphere of an inert gas and water vapor under irradiation of ultraviolet light from a dielectric barrier discharge lamp, thereby decomposing organic substances deposited on a surface of said substrate and at the same time splitting water vapor into a reducing active member [H·] (H·)and an oxidative active member [·OH] (·OH);

Inventor: Kazuto KINOSHITA, et al.
Preliminary Amendment filed with Divisional Application September 10, 2003

dry-washing and minimizing contact angle of a surface of said substrate by subjecting said reducing and oxidative active members [H·] (H·) and [·OH] (·OH) to reactions with decomposition products of said organic substances;

wet-washing siad said substrate by supplying a wash liquid thereto; and drying said substrate.